

MKPL impedance measurements with and without serigraphy

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MKP configuration





Beam induced power loss





MKP-I: Impedance considerations, C. Zannini et al., <u>LIU-SPS 50 ns Injection</u> <u>System for Pb Ions Review</u>, 4 October 2013 (<u>slides</u>).

Present MKPs could strongly suffer of beam induced heating with high intensity beam

2018 thermal behavior of MKPL, MKPS and MKE



Reached high temperatures even without dedicated scrubbing, just from nominal operation and high intensity studies on Thursdays

Operational Scenarios for SPS

| onfident: Bel | l <mark>ow Tc (Cur</mark> i | ie Te | mp.) | | | Designate | | | Dortosile Ci | overni. | Dumala 9 | Carla Zannin |
|---|-----------------------------|--------|----------|------------|-------|--------------|---------------|----------------------|-------------------------------------|------------|----------------|--------------|
| ould exceed Tc: risk of mis-kicking beam Basic table courtesy Hannes Bartosik, Glovanni Rumolo & Carlo Zannir | | | | | | | | | | | | |
| sk of mecha | nical dama | ge | | | | | | resulting average | resulting average power loss per | | | |
| ery low risk o | of damage | | Injected | Exrtracted | duty | | module length | power loss | module | duration | | Ferrite |
| ot OK (> Tc) ^{er} | nario | trains | p/b | p/b | cycle | cycle type | [m] | [W/m] | [W/module] | (hours) | repetition | Temperature |
| | 2018 operation | 3x48 | 1.33E+11 | 1.20E+11 | 50% | acceleration | 0.7 | 149 | 104 | 1.5 | every 12 hours | ОК |
| | 2018 MD | 4x48 | 1.80E+11 | 1.80E+11 | 50% | flat bottom | 0.7 | 164 | 115 | 10 | once per week | ОК |
| scrubbing week | 2021 scrubbing | 4x72 | 1.50E+11 | 1.50E+11 | 70% | flat bottom | 0.7 | 239 | 167 | continuous | continuous | ОК |
| typical week | 2021 operation | 4x48 | 1.44E+11 | 1.30E+11 | 50% | acceleration | 0.7 | 220 | 154 | 1.5 | every 12 hours | ОК |
| | 2021 MD | 4x72 | 1.67E+11 | 1.50E+11 | 50% | acceleration | 0.7 | 443 | 310 | 10 | once per week | ОК |
| scrubbing week | 2022 scrubbing | 4x72 | 2.00E+11 | 2.00E+11 | 70% | flat bottom | 0.7 | 424 | 297 | continuous | continuous | Exceeds TC |
| typical week | 2022 operation | 4x48 | 1.67E+11 | 1.50E+11 | 50% | acceleration | 0.7 | 296 | 207 | 1.5 | every 12 hours | ОК |
| | 2022 MD | 4x72 | 2.22E+11 | 2.00E+11 | 50% | acceleration | 0.7 | 783 | 548 | 10 | once per week | Close to TC |
| scrubbing week | 2023 scrubbing | 4x72 | 2.60E+11 | 2.60E+11 | 70% | flat bottom | 0.7 | 717 | 502 | continuous | continuous | Not OK |
| typical week | 2023 operation | 4x48 | 2.00E+11 | 1.80E+11 | 50% | acceleration | 0.7 | 424 | 297 | 1.5 | every 12 hours | Exceeds TC |
| | 2023 MD | 4x72 | 2.56E+11 | 2.30E+11 | 50% | acceleration | 0.7 | 1074 | 752 | 10 | once per week | Not OK |
| typical week | 2024 operation | 4x48 | 2.00E+11 | 1.80E+11 | 50% | acceleration | 0.7 | 424 | 297 | 1.5 | every 12 hours | Exceeds TC |
| | 2024 MD | 4x72 | 2.56E+11 | 2.30E+11 | 50% | acceleration | 0.7 | 1074 | 752 | 10 | once per week | Not OK |

MKP impedance reduction

Concept with longitudinal serigraphy exists (4, 5 and 6 stripes)



| - | 667.00 mr | | | | | | |
|----------|------------------------|-----------------------|--|--|--|--|--|
| | | | | | | | |
| | Q20 | PL per LHC fill cycle | | | | | |
| | MKP-L | 874 W | | | | | |
| | MKP-S | 234 W | | | | | |
| | MKP-L ser. (6 stripes) | 28 W | | | | | |
| | MKP-L ser. (4 stripes) | 99 W | | | | | |

Impact on beam stability has been studied and estimated to be negligible

C. Zannini, I. Karpov, Impact of new MKP-L serigraphy, summary from BD analysis. Presented at the LIU-SPS coordination meeting, March 2020.

MKP impedance measurements



MKP impedance measurements



probably due to the effect of wire and terminations

Summary

- The MKPL was predicted to suffer of beam induced heating with LIU beam already in 2013
 - 2018 temperature data confirm the criticality of the kicker
- The MKPL is expected to limit operation and scrubbing during run III
- Impedance mitigation solution is available and validated with impedance measurements
 - Ongoing: simulation of the measurement setup (C. Antuono)

Thank you very much for your attention